

Title (en)
CHUCKING SYSTEM FOR NANO-MANUFACTURING

Title (de)
AUFSPANNSYSTEM FÜR DIE NANOHERSTELLUNG

Title (fr)
SYSTEME DE MANDRIN DESTINE A LA NANO-FABRICATION

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Application
EP 06718240 A 20060112

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- US 4749905 A 20050131
- US 10820805 A 20050418

Abstract (en)
[origin: WO2006083518A2] The present invention is directed towards a chucking system, including, inter alia, a body having a surface with a pin extending therefrom having a throughway defined therein, and a land surrounding the protrusions defining a channel between the pin and the land. In a further embodiment, the body comprises a plurality of protrusions.

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Citation (search report)

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